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On April 15, 2002

TOWNSEND and TOWNSEND and CREW LLP

By: Michael

SECOND AMENDMENT UNDER 37 CFR 1.116 EXPEDITED PROCEDURE - EXAMINING GROUP 1763

PATENT
Attorney Docket No.: 1771X2T19930
TTC No.: 016301-019930

#30 HNE
4/29/02
MM

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

SEBASTIEN RAOUX et al.

Application No.: 08/988,246

Filed: December 1, 1997

For: METHOD AND APPARATUS FOR MONITORING AND ADJUSTING CHAMBER IMPEDANCE

Examiner: Rudy Zervigon

SECOND AMENDMENT UNDER 37 CFR 1.116 EXPEDITED PROCEDURE EXAMINING GROUP 1763

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Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Advisory Action dated March 15, 2002 in the above-identified application, Applicants respectfully request entry of the Amendment under 37 CFR § 1.116 filed on February 11, 2001, as repeated below.

IN THE CLAIMS:

Please amend claims 11, 16, and 20 as follows.

11. A substrate processing system comprising:
a deposition chamber comprising a reaction zone;

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